

This listing of claims replaces all prior versions, and listings, of claims in the application:

Listing of Claims:

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1. (Currently Amended) An apparatus for measuring a volume of a quantity of a liquid, comprising at least one chamber for receiving the liquid, which chamber comprises a bottom and upright side walls and at least two electrodes to connect to a voltage source and to a measuring system for determining the an electrical impedance between the electrodes, wherein the electrodes are incorporated in the bottom of the chamber, allowing the electrical impedance of the liquid itself to be determined.

2. (Previously Amended) An apparatus according to claim 1, wherein the bottom of the chamber is substantially formed by a glass substrate.

3. (Previously Amended) An apparatus according to claim 2, wherein the electrodes are provided on the glass substrate, and are embedded in an insulation layer provided on the glass substrate.

4. (Previously Amended) An apparatus according to claim 3, wherein the upright side walls are formed by etching insulation material provided on the insulation layer.

5. (Previously Amended) An apparatus according to claim 1, wherein the bottom of the chamber is substantially formed by a silicon wafer.

6. (Previously Amended) An apparatus according to claim 5, wherein the silicon wafer is provided with a first insulation layer.

7. (Previously Amended) An apparatus according to claim 6, wherein the electrodes are provided on the first insulation layer of the silicon wafer and are embedded in a second insulation layer, which is provided on the first insulation layer.

8. (Previously Amended) An apparatus according to claim 7, wherein the upright side walls are formed by etching insulation material provided on the second insulation layer.

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9. (Previously Amended) An apparatus according to claim 1, wherein the volume of said at least one chamber is maximally 2 nanolitres.

10. (Previously Amended) An apparatus according to claim 1, wherein said apparatus comprises a plurality of chambers arranged in an array.

11. (Previously Amended) An apparatus according to claim 1, wherein said apparatus is connected to an alternating voltage source having a frequency of at least approximately 15 kHz.

12. (Original) An apparatus according to claim 6, wherein said first insulation layer comprises SiO_2 .

13. (Original) An apparatus according to claim 7, wherein said second insulation layer comprises Si_3N_4 .
